Appendix I

**XPS analysis application form**

Application date:\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_ (yyyy/mm/dd) Case no. :\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_

|  |
| --- |
| Applicant name (CHI): (ENG) Service unit: Supervisor: Tel: Extension: Mobile: E-mail: Contact Address:\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_\_Number of sample / description: Payment：□Cash □Cheque □Wire transfer  |
|  | Sample 1 | Sample 2 | Sample 3 | Sample 4 | Sample 5 | Sample 6 |
| Naming |  |  |  |  |  |  |
| Conductivity? | □Good □Poor | □Good □Poor | □Good □Poor | □Good □Poor | □Good □Poor | □Good □Poor |
| Chemical constituent(s) |  |  |  |  |  |  |
| Surface texture (if any) |  |  |  |  |  |  |
| Radioactive? | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N |
| Magnetic? | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N |
| Toxic? | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N |
| Volatile? | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N |
| Vacuum contamination (Y/N) and precautions? | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N | □Y □N |
| Site of investigation |  |  |  |  |  |  |
| Will the samples cross contaminate with each other? |  |  |  |  |  |  |
| Sample form(Thin film/Powder/bulk…) |  |  |  |  |  |  |
| **Test(s) to be taken**  |
| 1.XPS survey scan (Range in eV) |  |  |  |  |  |  |
| 2.XPS Elemental spectra(State elements to be traced) |  |  |  |  |  |  |
| 3.Depth profiling (Please also state your desired endpoint. E.g. (20nm)/SiO2(100nm)/Si, Stop when Si signal shows up | □Ar □C60 | □Ar □C60 | □Ar □C60 | □Ar □C60 | □Ar □C60 | □Ar □C60 |
| 4. Pre-sputtering (in mins) |  |  |  |  |  |  |
| 5.Angle resolved analysis(State the angle if desired) |  |  |  |  |  |  |
| 6.SEI image |  |  |  |  |  |  |
| Remarks |  |  |  |  |  |  |

Notes to applicant：

* 1. Please read the X光光電子能譜儀(XPS)預約與管理辦法 prior to application。
	2. Contact the operator ASAP once your asmple arrive at the center.
	(Ms. Wei, email: yjwei2020@mail.mcut.edu.tw, Tel：02-2908-9899#4390)。
	3. Samples must be degassed for at least 30 mins before sent into XPS chamber.